



Applications

RTA (Rapid Thermal Annealing)
RTO (Rapid Thermal Oxidation)
Ohmic contact annealing
Implant annealing
RTCVD of graphene and hBN
Selenization, sulfurization
Crystallization and densification

The AS-One systems are available with two sizes of reactors to process substrates up to 100 mm (4") or 150 mm (6") diameter. The machine has been specially developed to meet the requirements of universities, research laboratories and small-scale production up to 10,000 wafers per year.

The high reliability guarantees low cost of ownership.

Pyrometer and thermocouple temperature measurements are standard features. The fast digital PID temperature controller provides accurate and repeatable thermal control across the temperature range.

The clam shell style design of the process chamber gives full access to the bedplate and provides easy access for loading and unloading the substrates and allows practical cleaning of the chamber.

Optional features

Graphite and silicon carbide coated susceptors Rough vacuum pump and turbo pump, automatic pressure control with throttle valve Fast cooling system, Selenization kits

Customer support

Outstanding customer support for hardware, software and process Efficient remote support using software diagnostic capabilities High expertise in RTP processes of our process engineers Capability to support customer for process optimization

Physical specifications

Voltage: 3x400V+N+Gr / 3x220V+Gr

Power: 30 kW (34 kW)

Facilities Water: 2 to 4 bars, pressure drop 1 bar, 10 l/mn (12 l/mn)

Compressed air: 6 bars (valve actuation)

Process gas fittings: double ferrule ¼ or VCR ¼ (option)

		AS-One 100		AS-One 150	
Dimensions and weight	Width	530 mm	21,0"	530 mm	21,0"
	Depth	800 mm	31,5"	800 mm	31,5"
	Height	1,425 mm	56,1"	1,425 mm	56,1"
	Mass	194 kg	428 lbs	206 kg	455 lbs





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